

ABSTRACT

**SUBSTRATE, METHOD OF PREPARING A SUBSTRATE, METHOD OF
MEASUREMENT, LITHOGRAPHIC APPARATUS, DEVICE
MANUFACTURING METHOD AND DEVICE MANUFACTURED
THEREBY, AND MACHINE-READABLE STORAGE MEDIUM**

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In a method according to one embodiment of the invention, a plurality of
10 markers are printed in resist on a substrate at a range of angles relative to a crystal axis
of the substrate. The markers are etched in to the substrate using an anisotropic etch
process, such that after the etch the apparent positions of the markers are dependent on
their orientation relative to the crystal axis. The apparent positions of the markers are
measured, and from this information the orientation of the crystal axis is derived.